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Examiner Signature	<i>Jessie Yuen</i>	Date Considered	2-28-07
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Substitute for form 1449A/PTO <b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b> (use as many sheets as necessary)				<b>Complete if Known</b>	
				Application Number	10/511,571
				Filing Date	October 12, 2004
				First Named Inventor	Paul Frederick Fewster
				Art Unit	2882
				Examiner Name	JURIE YUN
				Attorney Docket Number	5926P037
Sheet	2	of	2		

NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No. <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T <sup>2</sup>
J.Y.		"Grazing excidence diffraction versus grazing incidence diffraction for strain/stress evaluation in thin films" by ANOUAR NJEH et al.; <i>Powder Diffraction</i> 15 (4), December 2000; pp 211-216	
J.Y.		"Submicron x-ray diffraction and its applications to problems in materials and environmental science" by N. TAMURA et al.; <i>Review of Scientific Instruments</i> ; Volume 73, Number 3, March 2002; pp. 1369-1372	
J.Y.		"Submicron X-ray diffraction" by A.A. MacDowell et al.; <i>Nuclear Instruments and Methods in Physics Research A</i> 467-468 (2001); pp. 936-943	
J.Y.		"Crystallographic Analysis of CVD Films by Using X-Ray Polychromatic Radiation" by B. Lavelle, et al.; 1998 <i>Materials Research Society Symp. Proc.</i> Vol. 524; pp. 121-126	
J.Y.		"Image Plates as One-Dimensional Detectors in High-Resolution X-ray Diffraction" by A. KINNE et al.; <i>J. Appl. Cryst.</i> (1998); pp. 446-452	
J.Y.		"Real-time <i>in situ</i> x-ray diffraction as a method to control epitaxial growth" by A.S. BADER et al.; <i>Applied Physics Letters</i> , Volume 82 Number 26; June 30, 2003; pp. 4684-4686	

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